

Advancing Plasma-Based Technologies PLASMIONIQUE À l'Avant-Garde des Technologies Plasma

EVAD SeriesThermal Vapour Deposition Systems



Controlled evaporation of metals, dielectrics and organic materials using E-beam, Evaporation boats and Effusion cells for application to thin film deposition and epitaxial growth of materials. Large or table-top units with full computer controlled features allows thickness control with high precision. Glovebox integration also available.

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EVAD Series Specifications

| Chamber | Stainless steel Vertical cylindrical, D-shape or split chamber design Custom designed |
|----------------------------|---|
| Vacuum System | Turbomolecular or Cryogenic pumping system Dry scroll or two stage mechanical backing pump Wide-range gauge for pressure measurement (atm to 10⁻⁹ torr) Gate valve for chamber isolation |
| Substrate/Sample Holder | User defined size Heated mounting plate with PID control of temperature Adjustable vertical position |
| Evaporators | For metals: Boats chosen to suit material with dedicated Power Supply Multi-pocket e-beam with different crucible sizes Feedback control of evaporation rate via quartz microbalance deposition rate monitor For organics and LT evaporators: Knudsen effusion cell, resistive heating to over 800 °C Crucible material chosen to suit application PID control of evaporation temperature Power supply to 12VDC, 12A (typical) Integral shutter, manual or automatic Optional cooling |
| Process Control System | LabView®-based monitoring and control software User-friendly graphical user interface Plotting and data-logging Program mode for programming multi-step processes Alarms and safety interlocks, emergency shut-off |
| Supply requirements | Power: 120 VAC/208VAC/ 60Hz / 3 or local standards Cooling water Pressurized air (for pneumatic gate valve): 40-60 psig Purge/vent gas valve |

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